

03500.015382



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Mr. Brian L. Mutschler
TAKAHARU KONDO ET AL.)	
	:	Art Unit: 1753
Application No.: 09/866,665)	
	:	
Filed: May 30, 2001)	
	:	
For: SILICON-TYPE THIN FILM)	
FORMATION PROCESS, SILICON	:	
TYPE THIN FILM, AND)	
PHOTOVOLTAIC DEVICE	:	May 7, 2004

Commissioner for Patents
Mail Stop: AF
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

In response to the Office Action dated February 9, 2004, please amend the above-identified application as follows prior to the further examination thereof pursuant to the accompanying Request for Continued Examination.